

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Shen et al.	Group Art Unit: 1763
Application No: 09/507,629	Examiner: Allan W. Olsen
Confirmation No: 7912	Attorney Docket No:
Filed: February 18, 2000	001945 USA P03/ETCH/SILICON/JB1
Title: SELF-CLEANING PROCESS FOR ETCHING SILICON-CONTAINING MATERIAL	March 10, 2003 San Francisco, California

AMENDMENT IN RESPONSE TO NON-FINAL OFFICE ACTION

Assistant Commissioner for Patents
Washington, D.C. 20231

Via Facsimile Transmission
(703) 872-9310

Examiner Olsen:

This communication is in response to the Office Action mailed on
December 10, 2002, and is being timely filed within three months thereof.

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By <u>Abigail M. Cotton</u>	Date <u>March 10, 2003</u>
Abigail M. Cotton	